

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant(s): Wei, Ronghua, et al

Examiner: Erma C. Cameron

Serial No.: 10/811,485

Group Art Unit: 1762 Conf. No.: 8882

Filed: March 26, 2004

Docket: SWRI:003

Title: Method And Apparatus For Forming A Nitride Layer On A Biomedical Device

AMENDMENT

This is in response to the Official Action in this case mailed November 9, 2006. The Applicants petition for a two-month extension of time to extend the term for response from February 9, 2007 to April 9, 2007, as this response is being filed two-months after the three month shortened statutory period. In addition, Applicants conditionally petition for an additional extension of time to provide for the possibility that the need for such a petition has been inadvertently overlooked. Authorization to charge a credit card has been provided herewith via EFS. As provided below, please charge Deposit Account No. 50-2121 for any required fee, or for any deficiency in the enclosed fee.

Please amend the above referenced application as follows:

- Amendments to the Specification, beginning on Page 2 of this paper;
- Amendments to the Claims, beginning on Page 3 of this paper; and
- Remarks, beginning on Page 7 of this paper.